

Isaku Kanno

List of Publications by Year in descending order

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159
papers

3,338
citations

172386
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162
all docs

162
docs citations

162
times ranked

2734
citing authors

#	ARTICLE	IF	CITATIONS
1	A Review on Piezoelectric Energy Harvesting: Materials, Methods, and Circuits. Energy Harvesting and Systems, 2019, 4, 3-39.	1.7	288
2	Piezoelectric MEMS for energy harvesting. MRS Bulletin, 2012, 37, 1039-1050.	1.7	286
3	Measurement of transverse piezoelectric properties of PZT thin films. Sensors and Actuators A: Physical, 2003, 107, 68-74.	2.0	209
4	High-efficiency piezoelectric energy harvesters of c-axis-oriented epitaxial PZT films transferred onto stainless steel cantilevers. Sensors and Actuators A: Physical, 2010, 163, 428-432.	2.0	140
5	Characterization and aging response of the d_{31} piezoelectric coefficient of lead zirconate titanate thin films. Journal of Applied Physics, 1999, 85, 6711-6716.	1.1	121
6	Power-generation performance of lead-free (K,Na)NbO ₃ piezoelectric thin-film energy harvesters. Sensors and Actuators A: Physical, 2012, 179, 132-136.	2.0	118
7	Piezoelectric Properties of (K,Na)NbO ₃ Films Deposited by RF Magnetron Sputtering. Applied Physics Express, 2008, 1, 011501.	1.1	111
8	Pulsed Laser Deposition of High-Quality (K,Na)NbO ₃ Thin Films on SrTiO ₃ Substrate Using High-Density Ceramic Targets. Japanese Journal of Applied Physics, 2004, 43, 6627-6631.	0.8	103
9	Concepts for a new class of all-polymer micropumps. Lab on A Chip, 2006, 6, 1147.	3.1	98
10	Crystallographic characterization of epitaxial Pb(Zr,Ti)O ₃ films with different Zr/Ti ratio grown by radio-frequency-magnetron sputtering. Journal of Applied Physics, 2003, 93, 4091-4096.	1.1	93
11	Micro cell encapsulation and its hydrogel-beads production using microfluidic device. Microsystem Technologies, 2007, 13, 951-958.	1.2	78
12	Development of Deformable Mirror Composed of Piezoelectric Thin Films for Adaptive Optics. IEEE Journal of Selected Topics in Quantum Electronics, 2007, 13, 155-161.	1.9	73
13	Piezoelectric MEMS: Ferroelectric thin films for MEMS applications. Japanese Journal of Applied Physics, 2018, 57, 040101.	0.8	72
14	Low-Temperature Preparation of Pb(Zr, Ti)O ₃ Thin Films on (Pb, La)TiO ₃ Buffer Layer by Multi-Ion-Beam Sputtering. Japanese Journal of Applied Physics, 1993, 32, 4057-4060.	0.8	71
15	Comparison of effective transverse piezoelectric coefficients d_{31} and d_{31}^* of Pb(Zr,Ti)O ₃ thin films between direct and converse piezoelectric effects. Japanese Journal of Applied Physics, 2015, 54, 10NA04.	0.8	69
16	Thin-Film Piezoelectric Materials For a Better Energy Harvesting MEMS. Journal of Microelectromechanical Systems, 2012, 21, 451-457.	1.7	68
17	Antiferroelectric PbZrO ₃ thin films prepared by multi-ion-beam sputtering. Applied Physics Letters, 1995, 66, 145-147.	1.5	62
18	Characterization of Pb(Zr,Ti)O ₃ thin films deposited on stainless steel substrates by RF-magnetron sputtering for MEMS applications. Sensors and Actuators A: Physical, 2006, 125, 382-386.	2.0	53

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19	Thermodynamic study of c-axis-oriented epitaxial Pb(Zr,Ti)O ₃ thin films. Physical Review B, 2004, 69, .	1.1	52
20	Development of liquid pumping devices using vibrating microchannel walls. Sensors and Actuators A: Physical, 2009, 152, 211-218.	2.0	49
21	Lead-Free Piezoelectric MEMS Energy Harvesters of (K,Na)NbO ₃ Thin Films on Stainless Steel Cantilevers. Japanese Journal of Applied Physics, 2013, 52, 09KD13.	0.8	48
22	Piezoelectric properties of (K,Na)NbO ₃ thin films deposited on (001)SrRuO ₃ /Pt/MgO substrates. IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, 2007, 54, 2562-2556.	1.7	42
23	Colocalization of Quantum Dots by Reactive Molecules Carried by Motor Proteins on Polarized Microtubule Arrays. ACS Nano, 2013, 7, 447-455.	7.3	42
24	Piezoelectric Properties of Epitaxial NaNbO ₃ Thin Films Deposited on (001)SrRuO ₃ /Pt/MgO Substrates. Japanese Journal of Applied Physics, 2007, 46, 6960.	0.8	41
25	Simple Fabrication of Metal-Based Piezoelectric MEMS by Direct Deposition of $\text{Pb}(\text{Zr}, \text{Ti})\text{O}_3$ on Flexible Systems, 2009, 18, 610-615.	1.7	40
26	Nano-particle deposition system (NPDS): Low energy solvent-free dry spray process for direct patterning of metals and ceramics at room temperature. International Journal of Precision Engineering and Manufacturing, 2012, 13, 1107-1112.	1.1	40
27	Precise measurement of the transverse piezoelectric coefficient for thin films on anisotropic substrate. Journal of Applied Physics, 2013, 113, .	1.1	39
28	Fabrication and transverse piezoelectric characteristics of PZT thick-film actuators on alumina substrates. Sensors and Actuators A: Physical, 2008, 148, 134-137.	2.0	34
29	Deposition Of PZT Thin Films With (001), (110), and (111) Crystallographic Orientations And Their Transverse Piezoelectric Characteristics. Advanced Materials Letters, 2012, 3, 102-106.	0.3	32
30	Piezoelectric MEMS for energy harvesting. Journal of Physics: Conference Series, 2015, 660, 012001.	0.3	31
31	Crystalline Structure of Highly Piezoelectric (K,Na)NbO ₃ Films Deposited by RF Magnetron Sputtering. Japanese Journal of Applied Physics, 2008, 47, 8909.	0.8	28
32	Piezoelectric properties of microfabricated (K,Na)NbO ₃ thin films. Sensors and Actuators A: Physical, 2011, 171, 223-227.	2.0	28
33	Airflow energy harvester of piezoelectric thin-film bimorph using self-excited vibration. Sensors and Actuators A: Physical, 2017, 261, 295-301.	2.0	28
34	Preparation of c-Axis Oriented Pb(Zr,Ti)O ₃ Thin Films by RF-Magnetron Sputtering and their Dielectric and Piezoelectric Properties. Japanese Journal of Applied Physics, 1997, 36, 6065-6068.	0.8	26
35	Ferroelectric properties of Pb(Mn ^{1/3} Nb ^{2/3})O ₃ ~Pb(Zr,Ti)O ₃ thin films epitaxially grown on (001)MgO substrates. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2008, 26, 985-990.	0.9	26
36	Crystallographic contributions to piezoelectric properties in PZT thin films. Scientific Reports, 2019, 9, 7309.	1.6	26

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37	Highly polarized single-c-domain single-crystal $\text{Pb}(\text{Mn},\text{Nb})\text{O}_3$ -PZT thin films. IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, 2012, 59, 6-13.	1.7	24
38	Sol-gel deposition and piezoelectric properties of {110}-oriented $\text{Pb}(\text{Zr}_{0.52}\text{Ti}_{0.48})\text{O}_3$ thin films. Applied Physics Letters, 2010, 96, .	1.5	23
39	Orientation Dependence of Transverse Piezoelectric Properties of Epitaxial BaTiO_3 Films. Japanese Journal of Applied Physics, 2010, 49, 09MA09.	0.8	20
40	Development of a micro biochip integrated traveling wave micropumps and surface plasmon resonance imaging sensors. Microsystem Technologies, 2007, 13, 1391-1396.	1.2	19
41	Composition Dependence of Piezoelectric Properties of $\text{Pb}(\text{Zr},\text{Ti})\text{O}_3$ Films Prepared by Combinatorial Sputtering. Japanese Journal of Applied Physics, 2012, 51, 09LA12.	0.8	19
42	Characterization of $\text{Pb}(\text{Zr},\text{Ti})\text{O}_3$ Thin Films Prepared by Multi-Ion-Beam Sputtering. Japanese Journal of Applied Physics, 1994, 33, 574-577.	0.8	18
43	Limiting current type yttria-stabilized zirconia thin-film oxygen sensor with spiral Ta_2O_5 gas diffusion layer. Sensors and Actuators B: Chemical, 2021, 327, 128932.	4.0	18
44	Fabrication of single crystal PZT thin films on glass substrates. Vacuum, 2007, 81, 571-578.	1.6	17
45	Metal-based piezoelectric microelectromechanical systems scanner composed of $\text{Pb}(\text{Zr}, \text{Ti})\text{O}_3$ thin film on titanium substrate. Microsystem Technologies, 2012, 18, 765-771.	1.2	17
46	Transparent piezoelectric thin-film devices: $\text{Pb}(\text{Zr}, \text{Ti})\text{O}_3$ thin films on glass substrates. Sensors and Actuators A: Physical, 2021, 327, 112786.	2.0	16
47	Fabrication of High-Efficiency Piezoelectric Energy Harvesters of Epitaxial $\text{Pb}(\text{Zr},\text{Ti})\text{O}_3$ Thin Films by Laser Lift-off. Energy Harvesting and Systems, 2016, 3, 61-67.	1.7	15
48	Intrinsic crystalline structure of epitaxial $\text{Pb}(\text{Zr},\text{Ti})\text{O}_3$ thin films. Journal of Applied Physics, 2005, 97, 074101.	1.1	14
49	Ferroelectric PbTiO_3 Thin Films Prepared by Multi-Ion-Beam Sputter and Ion-Assisted Deposition. Japanese Journal of Applied Physics, 1993, 32, L950-L953.	0.8	13
50	Simple millimeter-scale robot using $\text{Pb}(\text{Zr}, \text{Ti})$ piezoelectric thin film actuator on titanium substrate. Microsystem Technologies, 2016, 22, 1429-1436.	1.2	13
51	Electromechanical properties of BaTiO_3 - $x\text{BaSnO}_3$ thin films prepared via combinatorial sputtering. Ceramics International, 2017, 43, 1597-1601.	2.3	13
52	Deposition and performance of all solid-state thin-film lithium-ion batteries composed of amorphous $\text{Si}/\text{LiPON}/\text{VO-LiPO}$ multilayers. Thin Solid Films, 2020, 697, 137840.	0.8	13
53	Compositional dependence of $\text{Ba}(\text{Zr}_{0.2}\text{Ti}_{0.8})\text{O}_3$ and $(\text{Ba}_{0.7}\text{Ca}_{0.3})\text{TiO}_3$ piezoelectric thin films prepared by combinatorial sputtering. Thin Solid Films, 2015, 588, 34-38.	0.8	12
54	Structural investigation of $\text{Pb}(\text{Zr}_{0.57}\text{Ti}_{0.43})_2$ films deposited on $\text{Pt}(001)/\text{MgO}(001)$ substrates by rf sputtering. Physical Review B, 2002, 66, .	1.1	11

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55	Evaluation of Intrinsic Shear Piezoelectric Coefficient of c-Axis Oriented Pb(Zr,Ti)O ₃ Films. Applied Physics Express, 2009, 2, 091402.	1.1	11
56	Perfusable multi-scale channels fabricated by integration of nanoimprint lithography (NIL) and UV lithography (UVL). Microelectronic Engineering, 2012, 98, 58-63.	1.1	11
57	A perfusable microfluidic device with on-chip total internal reflection fluorescence microscopy (TIRFM) for in situ and real-time monitoring of live cells. Biomedical Microdevices, 2012, 14, 791-797.	1.4	11
58	Ultrahigh temperature platinum microheater encapsulated by reduced-TiO ₂ barrier layer. Sensors and Actuators A: Physical, 2019, 296, 286-291.	2.0	11
59	Influence of lithium doping on the structural and electrical characteristics of ZnO thin films. Thin Solid Films, 2012, 520, 5797-5800.	0.8	10
60	Probing domain switching dynamics in ferroelectric thick films by small field piezoelectric measurement. Applied Physics Letters, 2017, 111, 022904.	1.5	10
61	Basic sputtering process and ferroelectric properties of single-domain crystal thin films of PbTiO ₃ . Integrated Ferroelectrics, 1998, 21, 451-460.	0.3	9
62	Structure and Electromechanical Properties of Quenched PMN-PT Single Crystal Thin Films. Advances in Science and Technology, 2006, 45, 1212-1217.	0.2	9
63	High Throughput Cell Electroporation Array Fabricated by Single-Mask Inclined UV Lithography Exposure and Oxygen Plasma Etching. , 2007, , .		9
64	Multilayer Thin-Film Capacitor Fabricated by Radio-Frequency Magnetron Sputtering. Japanese Journal of Applied Physics, 2011, 50, 09NA01.	0.8	9
65	In Situ XRD Observation of Crystal Deformation of Piezoelectric (K,Na)NbO ₃ Thin Films. ACS Applied Electronic Materials, 2020, 2, 2084-2089.	2.0	9
66	Composition Dependence of Piezoelectric Properties of Pb(Zr,Ti)O ₃ Films Prepared by Combinatorial Sputtering. Japanese Journal of Applied Physics, 2012, 51, 09LA12.	0.8	9
67	Preparation of Pb-Based Ferroelectric Thin Films at Room Temperature Using Excimer-Laser-Assisted Multi-Ion-Beam Sputtering. Japanese Journal of Applied Physics, 1995, 34, 5211-5215.	0.8	8
68	Orientation Dependence of Shear Mode Piezoelectric Properties of Epitaxial Pb(Zr _x Ti _{1-x})O ₃ Thin Films. Japanese Journal of Applied Physics, 2010, 49, 09MA07.	0.8	8
69	Piezoelectric vibration energy harvesters with stretched and multistacked organic ferroelectric films. Japanese Journal of Applied Physics, 2017, 56, 04CL04.	0.8	8
70	Compositional dependence of Pb(Mg _{1/3} ,Nb _{2/3})O ₃ piezoelectric thin films by combinatorial sputtering. Japanese Journal of Applied Physics, 2014, 53, 09PA06.	0.8	7
71	Improved transverse piezoelectric properties in {110}-oriented B-site acceptor doped PLZT (8/65/35) thin films. Integrated Ferroelectrics, 2016, 176, 210-219.	0.3	7
72	Vibration energy harvester with piezoelectric properties using polyurea thin films. Molecular Crystals and Liquid Crystals, 2017, 653, 188-193.	0.4	6

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73	Piezoelectric Pzt Thin Films: Deposition, Evaluation and Their Applications. , 2019, , .		6
74	Highly (001)-textured BiFeO ₃ thick films integrated on stainless steel foils with an optimized piezoelectric performance. Journal of the European Ceramic Society, 2022, 42, 3454-3462.	2.8	6
75	Electric Field-Induced Strain of PbZrO ₃ Films. Japanese Journal of Applied Physics, 2006, 45, 7258-7261.	0.8	5
76	Growth and structure of heteroepitaxial lead titanate thin films constrained by miscut strontium titanate substrates. Journal of Materials Research, 2006, 21, 1261-1268.	1.2	5
77	Development of piezoelectric MEMS deformable mirror. Microsystem Technologies, 2011, 17, 931-935.	1.2	5
78	Transverse piezoelectric properties of {100} \hat{a} Oriented PLZT[x/65/35] thin films. Materials Chemistry and Physics, 2015, 151, 308-311.	2.0	5
79	Electric Power Generation from Environmental Vibration (Vibration Energy Harvesting). Hyomen Cijutsu/Journal of the Surface Finishing Society of Japan, 2016, 67, 348-352.	0.1	5
80	Finger flexion power generators made of piezoelectric lead zirconate titanate thin films on stainless steel foils. Sensors and Actuators A: Physical, 2021, 322, 112617.	2.0	5
81	Piezoelectric properties of (K, Na)NbO ₃ thin films deposited on (001)SrRuO ₃ /Pt/MgO substrates. Applications of Ferroelectrics, IEEE International Symposium on, 2007, , .	0.0	4
82	Piezoelectric unimorph microactuators with X-shaped structure composed of PZT thin films. Microsystem Technologies, 2007, 13, 825-829.	1.2	4
83	Dry Etching of Lead-Free (K,Na)NbO ₃ Piezoelectric Films by Ar/C ₄ F ₈ Plasma. Japanese Journal of Applied Physics, 2012, 51, 076202.	0.8	4
84	Piezoelectric unimorph microcantilevers for measuring direct and converse piezoelectric coefficients. Journal of Applied Physics, 2021, 130, .	1.1	4
85	Piezoelectric PZT thin-film transformers with a ring $\dot{\circ}$ structure. Japanese Journal of Applied Physics, 2020, 59, SPPD09.	0.8	4
86	Development of Atomization Method in Microchannel and Its Basic Characteristics. 880-02 Nihon Kikai Gakkai Ronbunsh \hat{a} Transactions of the Japan Society of Mechanical Engineers Series B B-hen, 2005, 71, 2007-2012.	0.2	3
87	Modal Analysis for Externally Driven Micropump and Additional Mass Effect of Water. Japanese Journal of Applied Physics, 2008, 47, 5226-5230.	0.8	3
88	Measuring the force of adhesion between multiple kinesins and a microtubule using the fluid force produced by microfluidic flow. Microfluidics and Nanofluidics, 2011, 11, 519-527.	1.0	3
89	Multilayer La-modified PbTiO ₃ capacitors via RF magnetron sputtering. Journal of Materials Science, 2015, 50, 3631-3637.	1.7	3
90	Precise piezoelectric characterization of Pb(Hf,Ti)O ₃ thin films deposited by combinatorial sputtering. Thin Solid Films, 2016, 616, 444-448.	0.8	3

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91	Piezoelectric characterization of $\text{Pb}(\text{Zr,Ti})\text{O}_3$ thin films deposited on metal foil substrates by dip coating. Japanese Journal of Applied Physics, 2017, 56, 10PF08.	0.8	3
92	Immediate elimination of injured white matter tissue achieves a rapid axonal growth across the severed spinal cord in adult rats. Neuroscience Research, 2018, 131, 19-29.	1.0	3
93	Numerical designs of piezoelectric thin-film vibration energy harvesters. Japanese Journal of Applied Physics, 2018, 57, 11UD06.	0.8	3
94	Ternary perovskite thin films for energy harvesting MEMS. , 2010, , .		2
95	On-chip force measurement system for investigating plant-root growth. , 2014, , .		2
96	High-productive fabrication method of flexible piezoelectric substrate. , 2015, , .		2
97	Fabrication of piezoelectric multilayer thin-film actuators. Microsystem Technologies, 2016, 22, 1275-1283.	1.2	2
98	Transverse piezoelectric properties of {110}-oriented PLZT thin films. Integrated Ferroelectrics, 2018, 192, 113-120.	0.3	2
99	Multilayer Thin-Film Capacitor Fabricated by Radio-Frequency Magnetron Sputtering. Japanese Journal of Applied Physics, 2011, 50, 09NA01.	0.8	2
100	MCH-01 DEVELOPMENT OF A NOVEL METHOD FOR STRETCHING DNA FIBERS ON MICROBRIDGES FABRICATED BY SINGLE-MASK INCLINED UV LITHOGRAPHY(Micro/Nanomechatronics I,Technical Program of Oral) Tj ETQq0 0 0 rgBT /Overlock 10 Tf 5 Information and Precision Equipment IIP/ISPS Joint. MIPE, 2009, 2009, 325-326.	0.0	2
101	Limiting current-type MEMS oxygen gas sensor integrated with micro-hotplate. , 2021, , .		2
102	Bias-free Photo-electrochemical Water Splitting Driven by Large Photopotential of Epitaxial $(\text{Pb,L a})\text{TiO}_3$ Ferroelectric Thin Films. ACS Applied Energy Materials, 2022, 5, 2606-2612.	2.5	2
103	High-energy ion beam analysis of ferroelectric thin films. Applied Surface Science, 1997, 117-118, 453-458.	3.1	1
104	Characterization of Transverse Piezoelectric Properties of c-Axis Oriented PbTiO_3 Thin Films. Ferroelectrics, 2005, 327, 91-95.	0.3	1
105	Genetic Extended-Fiber Network (GEN) Stretched Over Microbridges Fabricated by Single-Mask Inclined UV Lithography. , 2007, , .		1
106	High-density piezoelectric actuator array for MEMS deformable mirrors composed of PZT thin films. , 2008, , .		1
107	Thin Film MEMS. , 2012, , 559-596.		1
108	Early characterization method of plant root adaptability to soil environments. , 2015, , .		1

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109	Composition dependence of transverse piezoelectric properties of preferentially {110}-oriented (1 \times) PIN-x PT thin films. Journal of Alloys and Compounds, 2016, 688, 863-867.	2.8	1
110	Structural optimization of piezoelectric thin-film vibration energy harvesters based on electric equivalent circuit model. , 2019, , 161-179.		1
111	Influence of Zr/Sn ratio on the Transverse Piezoelectric Coefficient [Inline formula] in Lanthanum-Doped Lead Zirconate Titanate Stannate Thin Films. Integrated Ferroelectrics, 2019, 201, 86-93.	0.3	1
112	An evaluation method for direct piezoelectric coefficients of thin films using both-ends-hinge-supported unimorph beams. Japanese Journal of Applied Physics, 2020, 59, SPPB04.	0.8	1
113	Micro liquid mixing using pulsating flow at extremely low Reynolds numbers. The Proceedings of the JSME Annual Meeting, 2004, 2004.2, 67-68.	0.0	1
114	Fabrication of all-solid-state amorphous thin-film Lithium-ion batteries. , 2021, , .		1
115	Development of Piezoelectric RF-MEMS Switch Driven by Low Operating Voltage. , 2005, , 2033.		0
116	Characteristics of Liquids Mixing and Mass Transfer in Passivemixer for .MU.TAS. 880-02 Nihon Kikai Gakkai RonbunshÅ« Transactions of the Japan Society of Mechanical Engineers Series B B-hen, 2005, 71, 111-116.	0.2	0
117	Shear piezoelectric coefficient d$\inf\>15$/$\inf\>3$ of c-axis oriented epitaxial Pb(Zr,Ti)O$\inf\>3$ films. , 2011, , .		0
118	Selective kinesin and dynein immobilization and electrical microtubule manipulation for bidirectional microtubule motility. , 2011, , .		0
119	Multilayer thin-film capacitors fabricated by radio-frequency magnetron sputtering. , 2011, , .		0
120	Design of MEMS cylindrical gyroscope integrated with piezoelectric thin film. , 2013, , .		0
121	Modeling of metal-based piezoelectric MEMS energy harvesters. , 2013, , .		0
122	Piezoelectric Thin-Film Actuators. Hyomen Gijutsu/Journal of the Surface Finishing Society of Japan, 2017, 68, 387-391.	0.1	0
123	Fundamentals of piezoelectric thin films for microelectromechanical systems. , 2019, , 237-255.		0
124	Equivalent circuit model of piezoelectric vibration energy harvesters composed of trapezoidal unimorph cantilevers. Journal of Physics: Conference Series, 2019, 1407, 012079.	0.3	0
125	Method for Analyzing an Infection Process of Plant-parasitic Nematodes Using a Microfluidic Device. IEEJ Transactions on Sensors and Micromachines, 2021, 141, 141-146.	0.0	0
126	A passive micromixer based on instability theory of interfacial wave growth. The Proceedings of the Bioengineering Conference Annual Meeting of BED/JSME, 2003, 2003.15, 231-232.	0.0	0

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127	Fabrication of Micro Actuator using piezoelectric thin films. The Proceedings of the JSME Annual Meeting, 2003, 2003.7, 225-226.	0.0	0
128	Computer aided design of passive mixer for $\hat{1}/4$ TAS. The Proceedings of the JSME Annual Meeting, 2003, 2003.5, 325-326.	0.0	0
129	Optimization of droplet generating method in a microchannel based on instability theory. The Proceedings of the JSME Annual Meeting, 2004, 2004.2, 69-70.	0.0	0
130	Measurement of electrical and mechanical properties of a living cardiac myocyte using MEMS device. The Proceedings of the JSME Annual Meeting, 2004, 2004.5, 341-342.	0.0	0
131	Development of Thin Film Valveless Micropump Driven by Traveling Wave. The Proceedings of the JSME Annual Meeting, 2004, 2004.7, 357-358.	0.0	0
132	2407 Measurement of mechanical properties of a single myocyte using MEMS technique. The Proceedings of the JSME Annual Meeting, 2005, 2005.7, 127-128.	0.0	0
133	1117 Measurement of electrophysiological properties of a single cell using MEMS device. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2005, 2005, 86-87.	0.0	0
134	2506 Development of measuring system for contraction characteristics of a single cardiac myocyte. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2005, 2005, 345-346.	0.0	0
135	914 Transfer method of PZT epitaxial thin films onto glass substrates and evaluation of their dielectric properties. The Proceedings of Conference of Kansai Branch, 2005, 2005.80, _9-27_-_9-28_.	0.0	0
136	2402 Deformable MEMS mirror using PZT thin film for adaptive optics. The Proceedings of the JSME Annual Meeting, 2005, 2005.7, 117-118.	0.0	0
137	2404 Development of fixed-fixed beam type RF-MEMS switches using the piezoelectric thin film. The Proceedings of the JSME Annual Meeting, 2005, 2005.7, 121-122.	0.0	0
138	1119 Development of micro atomizer and its computer aided design. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2005, 2005, 90-92.	0.0	0
139	5517 Deformable MEMS mirror using piezoelectric thin film for adaptive optics. The Proceedings of the JSME Annual Meeting, 2006, 2006.7, 319-320.	0.0	0
140	5518 Piezoelectric RF-MEMS switches using X type connectors. The Proceedings of the JSME Annual Meeting, 2006, 2006.7, 321-322.	0.0	0
141	5504 Single-MASK Inclined UV Lithography for Cell Analysis on a Microchip. The Proceedings of the JSME Annual Meeting, 2006, 2006.7, 293-294.	0.0	0
142	MEMS Deformable Mirrors for Adaptive Optics Actuated by Piezoelectric PZT Films. IEEJ Transactions on Sensors and Micromachines, 2007, 127, 518-523.	0.0	0
143	3304 Designing piezoelectric deformable mirror by using FEM simulation. The Proceedings of the JSME Annual Meeting, 2007, 2007.7, 295-296.	0.0	0
144	2107 High-resolution Piezoelectric Deformable Mirror for Adaptive Optics. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2008, 2008, 228-231.	0.0	0

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145	309 High-density piezoelectric MEMS deformable mirror for adaptive optics. The Proceedings of the JSME Annual Meeting, 2008, 2008.8, 17-18.	0.0	0
146	P-MCH-04 Piezoelectric micropumping system using PZT thin films(Micro/Nanomechatronics,Technical) Tj ETQq0 0 0 rgBT /Overlock 10 Micromechatronics for Information and Precision Equipment IIP/ISPS Joint MIPE, 2009, 2009, 387-388.	0.0	0
147	M5-3 Fabrication of PZT thin-film actuator by surface-machining process (M5 Actuator and Physical) Tj ETQq1 1 0.784314 rgBT /Overlock 10	0.0	0
148	T1601-2-1 Development of piezoelectric MEMS deformable mirrors and their application for adaptive optics. The Proceedings of the JSME Annual Meeting, 2009, 2009.8, 245-246.	0.0	0
149	T1601-1-3 Development of piezoelectric MEMS deformable mirrors and their application for adaptive optics. The Proceedings of the JSME Annual Meeting, 2009, 2009.8, 237-238.	0.0	0
150	J0207-2-1 Heterotypic cell positioning using electroosmotic flow and observation of cell-cell interactions. The Proceedings of the JSME Annual Meeting, 2010, 2010.6, 239-240.	0.0	0
151	B-4 Fabrication of optical communication device with piezoelectric micro mirror array. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2010, 2010, 73-74.	0.0	0
152	T1601-1-4 Fabrication of piezoelectric cantilever-shaped actuators with lead-free KNbO ₃ -NaNbO ₃ thin films. The Proceedings of the JSME Annual Meeting, 2010, 2010.8, 193-194.	0.0	0
153	J0207-1-6 Bi-directional transport of motor protein by electrophoresis. The Proceedings of the JSME Annual Meeting, 2010, 2010.6, 135-136.	0.0	0
154	D-2-1 Fabrication of Sub-micrometer Channels for Bio-assay Perfusion Device by Integrating Nanoimprint Lithography and UV Lithography. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2011, 2011, 28-29.	0.0	0
155	OS4-1-1 Piezoelectric energy harvesters of PZT films deposited on stainless steel. The Proceedings of the Symposium on Micro-Nano Science and Technology, 2012, 2012.4, 91-92.	0.0	0
156	21am2-A8 Transfer process of piezoelectric thin films onto PDMS substrate by using wet etching. The Proceedings of the Symposium on Micro-Nano Science and Technology, 2014, 2014.6, _21am2-A8--_21am2-A8-.	0.0	0
157	20pm1-E3 Fabrication of millimeter-scale robot with piezoelectric thin film actuator on metal substrate. The Proceedings of the Symposium on Micro-Nano Science and Technology, 2014, 2014.6, _20pm1-E3--_20pm1-E3-.	0.0	0
158	Characterization of Cylindrical Type MEMS Gyroscope Using Piezoelectric Thin-film Resonator. The Proceedings of Mechanical Engineering Congress Japan, 2016, 2016, J2230103.	0.0	0
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